

FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			ATTY DOCKET NO. 03500.017986.	APPLICATION NO. 10/550,450			
			APPLICANT YOSHIKATSU ICHIMURA, et al.				
			FILING DATE September 26, 2005	GROUP 2858			
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
JZ		4,205,267	05/1980	Williams	324	458	
		5,212,451	05/1993	Werner, Jr.	324	458	
		5,504,356	04/1996	Takeuchi, et al.	257	254	
		2003/0057977	03/2003	Werner, Jr., et al.	324	754	
		2006/0171728	08/2006	Ichimura, et al.	399	48	
↓		2006/0192565	08/2006	Yasuda, et al.	324	458	
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
JZ		2715831	10/1978	Germany			No
		10044887	05/2001	Germany			Abstract
		1003044	05/2000	Europe			
		2-071166	03/1990	Japan			Abstract
		4-025764	01/1992	Japan			Abstract
↓		6-196721	07/1994	Japan			Abstract
		6-196722	07/1994	Japan			Abstract
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
JZ		HSU C. H. et al: "Micromechanical electrostatic voltmeter "TRANSDUCERS. SAN FRANCISCO, JUNE 24-27, 1991, PROCEEDINGS OF THE INTERNATIONAL CONFERENCE ON SOLID STATE SENSORS AND ACTUATORS, NEW YORK, IEEE, US, vol. CONF. 6, 24 JUNE 1991 (1991-06-24), pages 659-662					
JZ		RIEHL P.S. "Microsystems for Electrostatic Sensing" DISSERTATION, Onlined November 2002 (2002-11) Page 1-8, 32-40, 79-84 (http://www-bsac.eecs.berkeley.edu/publications/search/zoom.php?urltimestamp=1040564878)					
EXAMINER	/John Zhu/			DATE CONSIDERED	01/11/2007		

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.